

EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	565	indium same tin same precursor same film	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:01
S2	194	transparent same conductive same film same (indium tin antimony aluminum zinc) same precursor	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:09
S3	20	baking same aluminum same precursor same pressure	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:56
S4	208	baking same aluminum same precursor	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:56
S5	16	baking same aluminum same precursor same nitrogen	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:56
S6	10	evaporating same aluminum same precursor same nitrogen	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:57
S7	402	heating same aluminum same precursor same nitrogen	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:57

S8	442	heating same aluminum same precursor same film	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:57
S9	46	heating same aluminum same precursor same film same nitrogen	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:57
S10	287	aluminum same precursor same solvent same remove	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:58
S11	430976	aluminum same oxide precursor same solvent same remove	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:58
S12	102	aluminum same oxide same precursor same solvent same remove	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 13:58
S13	367	aluminum same precursor same solvent same evaporat\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:02
S14	959	aluminum same precursor same solvent same heat \$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:04
S15	378	aluminum same oxide same precursor same solvent same heat \$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:05

S16	49	aluminum same oxide same precursor same (bake baking anneal annealing) same pressure	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:06
S17	103	aluminum same precursor same (bake baking anneal annealing) same pressure	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:06
S18	686	(aluminum same (bake baking anneal annealing) same pressure) and transparent	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:07
S19	11	(aluminum same precursor same (bake baking anneal annealing) same pressure) and transparent	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:07
S20	337	(aluminum same oxide same (bake baking anneal annealing) same pressure) and transparent	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:08
S21	427382	aluminum same oxide	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:10
S22	4738609	precursor or dispersion or liquid	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:10
S23	57672	S21 same S22	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:10

S24	5904990	bake baking anneal annealing heat heating evaporate evaporation evaporating	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:11
S25	17862	S23 same S24	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:11
S26	7489	S25 same (pressure vacuum)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:11
S27	3031	S26 same (nitrogen inert rare)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:12
S28	205	S27 not liquid	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:12
S29	628	S27 same (precursor dispersion)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:13
S30	248	S27 and transparent	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:13
S31	427382	aluminum same oxide	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:18

S32	312476	transparent same film	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:18
S33	10450	S31 same S32	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:18
S34	1741	S33 same S22	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:19
S35	550	S34 same S24	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 14:19
S36	550	S34 same S24	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 15:00
S37	10450	transparent same aluminum same oxide same film	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 15:09
S38	19	S37 and S29	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 15:09
S39	875	remove same solvent same vacuum same enhanc\$4	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 15:10

S40	204	remove same solvent same vacuum same enhanc\$4 same metal	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 15:11
S41	921	(bake baking anneal annealing baked annealed) same (aluminum same oxide) same (vacuum reduced low) same (nitrogen rare inert)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 15:14
S42	108	(bake baking anneal annealing baked annealed) same (aluminum same oxide) same (vacuum reduced low) same (nitrogen rare inert) and (dispersion precursor) and liquid	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 15:14
S43	44	transparent same (conducting conductive) same film same (precursor dispersion) same (bake baking baked anneal annealing annealed heat heating heated) same (nitrogen inert rare)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 15:17
S44	550	(427/248.1-255.7).cccls. and (transparent same (conductive conducting) same (film layer coating))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/01/02 16:00

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